

Substitute Form PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office		Attorney's Docket No. 07977-024003		Application No. New Divisional Application	
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))				Applicant Isamu Kobori et al.			
				Filing Date July 22, 2003		Group Art Unit Unknown	
U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
SDF	AA	5,413,958	05/1995	Imahashi et al.			
	AB	5,529,630	06/1996	Imahashi et al.			
	AC	5,595,923	01/1997	Zhang et al.			
	AD	5,767,930	06/1998	Kobayashi et al.			
	AE	5,854,494	05/1995	Yamazaki et al.			
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	AL	6,051,453	04/2000	Takemura			
	AM	6,071,764	06/2000	Zhang et al.			

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
SDF	AN	05,009,089 A	01/1993	Japan				
	AO	01-222432	09/1989	Japan				
	AP	06-260643	09/1994	Japan				

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
SDF	AQ	Y. Fukushima et al.; "A Poly-Si TFT Process for High Speed and Low Voltage CMOS Circuits"; <i>Extended Abstracts of the 1993 International Conference on Solid State Devices and Materials,</i> <i>Makuhari</i> ; pp. 993-995; 1993
	AR	
	AS	
	AT	

Examiner Signature <i>Stareta</i>	Date Considered 7/10/05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	